

nanoETCH

Soft-etching system for 2D materials.

ソフトエッチング装置 Model. ETCH5A

グラフェン・TMDC等の2Dアプリケーション、PPA・PMMA等のレジスト除去、テフロン基板などへのダメージレスエッチング

MOORFIELD
NANOTECHNOLOGY



(開発元：英国 Moorfield Nanotechnology Ltd.)

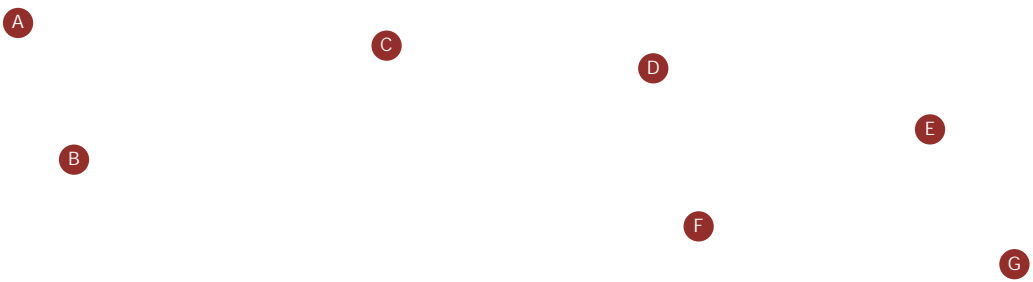


endless possibility_thermal engineering

www.thermocera.com

nanoETCH Model. ETCH5A

2/24



A
B
C

D
E
F
G

High Precision
Etching

ó BFD BEDI nanoETCH RIE

31 23% 20%

- 20%
- 10%
- 5%
- 2%
- 1%

7i 07/17	
1-10	01/01
10-20	70%
20-30	80%
30-40	90%
40-50	95%
50-60	98%
60-70	99%
70-80	99.5%
80-90	99.8%
90-100	99.9%

† æ ä Facility Requirement	
0	70l
10	100
20	150
30	200
40	250
50	300
60	350
70	400
80	450
90	500
100	550



nanoETCH

• 10

• 20

• 30